

Resistive Switching Memory Technologies

An Chen

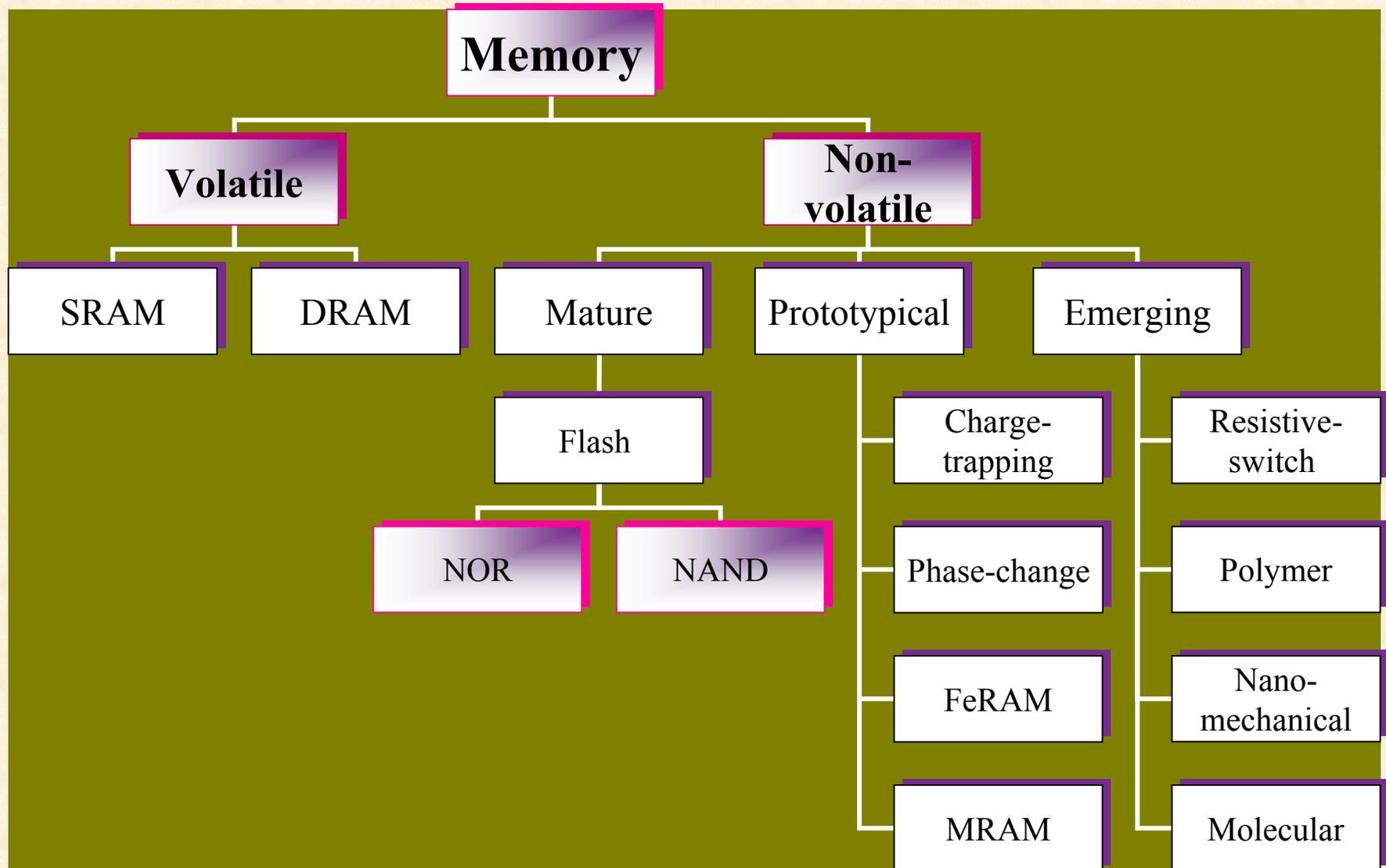
Strategic Technology Group

Advanced Micro Devices (AMD)

Outline

- Memory technologies
 - Category and characteristics
- Resistive switching memories
 - Resistive switching mechanisms
 - Device characteristics
- Ionic memory
 - Resistive switching in solid-state electrolytes
 - Device and array characteristics
 - Advantages *vs.* challenges
- Resistive switching devices for logic applications
- Summary

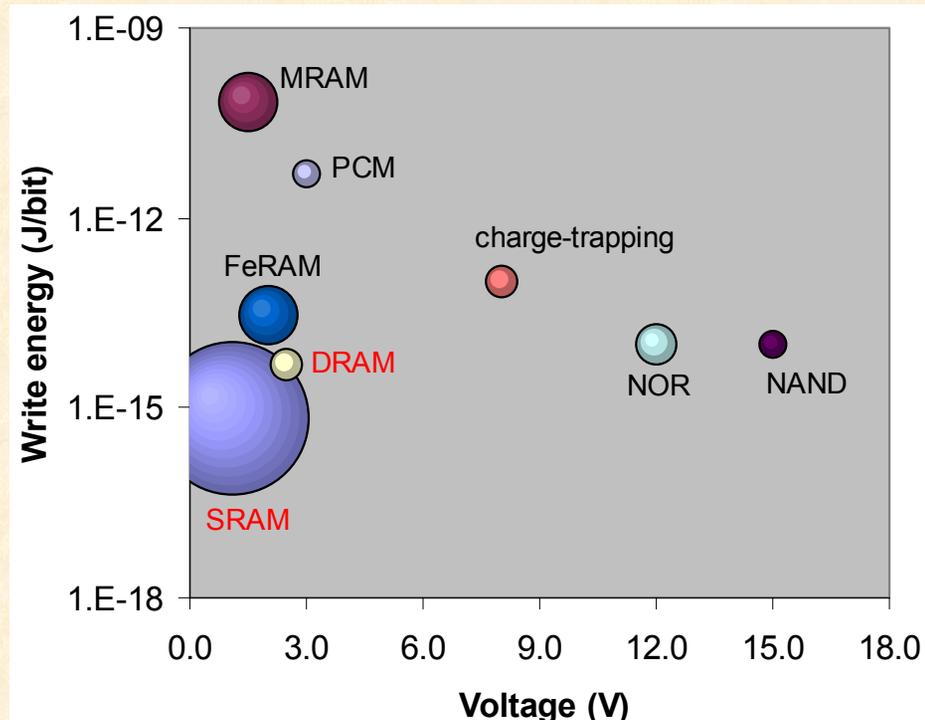
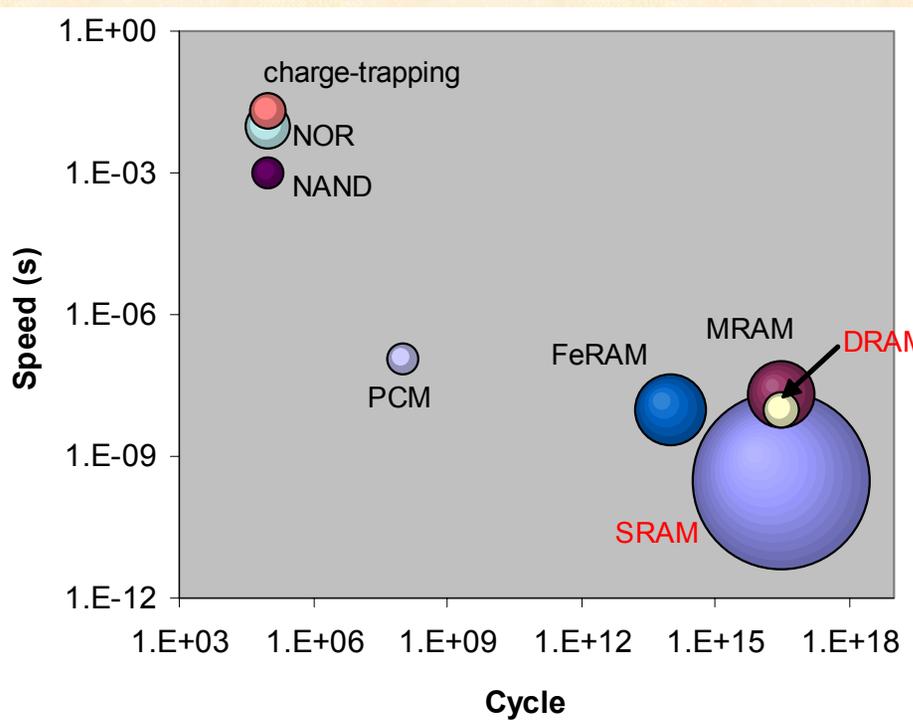
Memory Technologies



Baseline and Prototypical Memory Technologies

- Mature non-volatile memories (e.g., NAND, NOR) are relatively slow in speed, have limited cycling endurance, and high operating voltage
- Novel memory technologies have certain advantages, but also face challenges

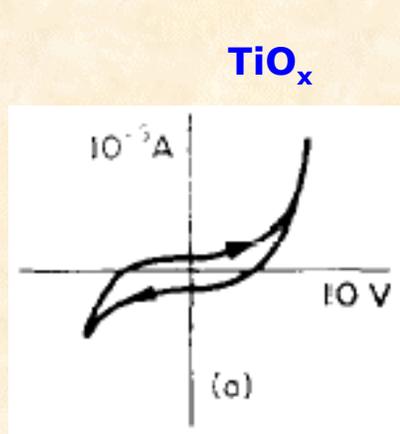
speed – cycling endurance – write energy – operation voltage – size



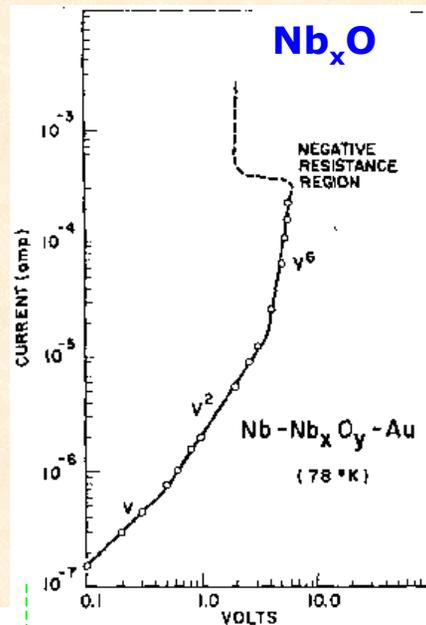
* The symbol size is proportional to the cell size of each memory device

ITRS Emerging Research Device Report (2007)

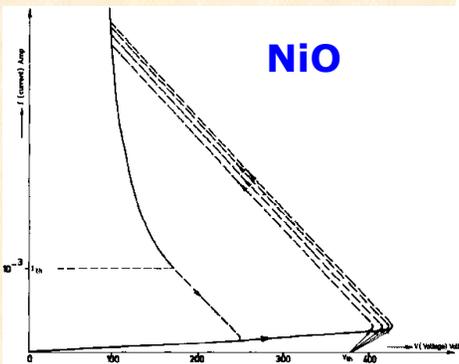
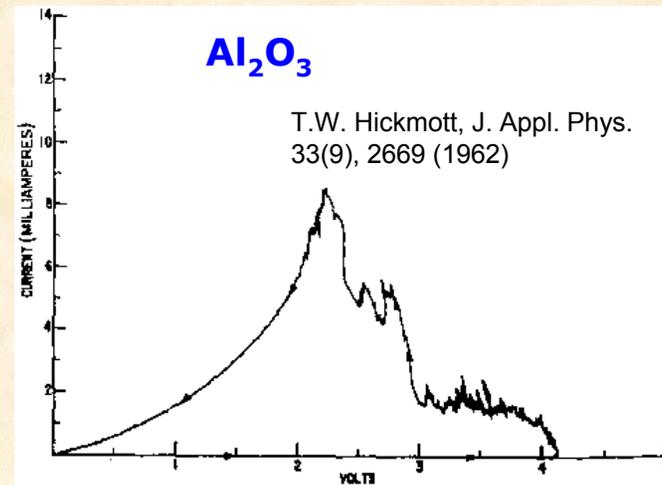
Early Report of Resistive Switching in Oxides



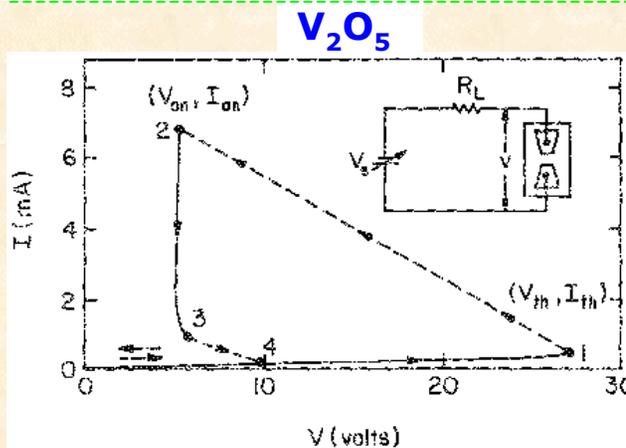
F. Argall, Solid State Electron. 11, 535 (1968)



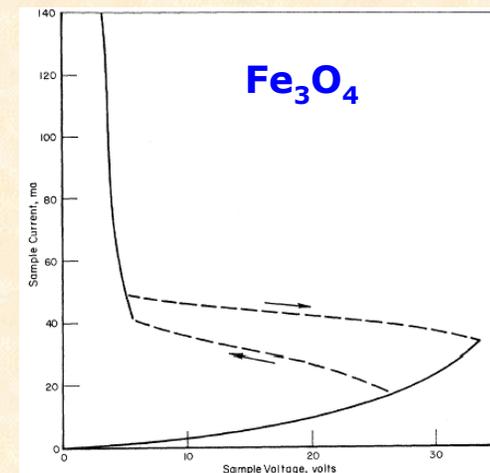
K.L. Chopra, J. Appl. Phys. 16(1), 184 (1965)



J.C. Bruyere, et al., Appl. Phys. Lett. 16(1), 40 (1970)



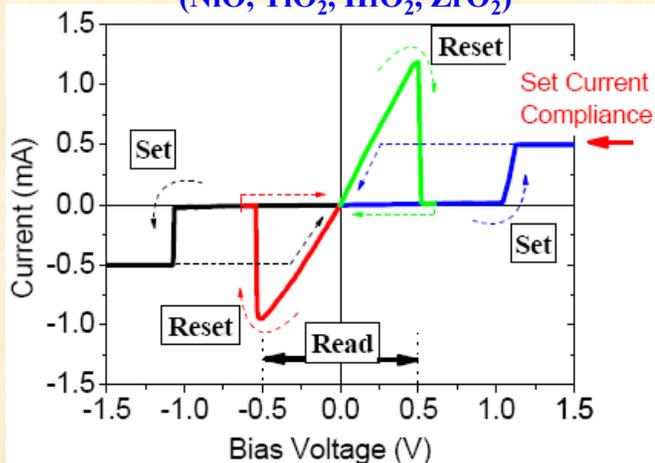
J.G. Zhang, et al., J. Appl. Phys. 64(2), 729 (1988)



P.J. Freud, et al., Phys. Rev. Lett. 23(25), 1440 (1969)

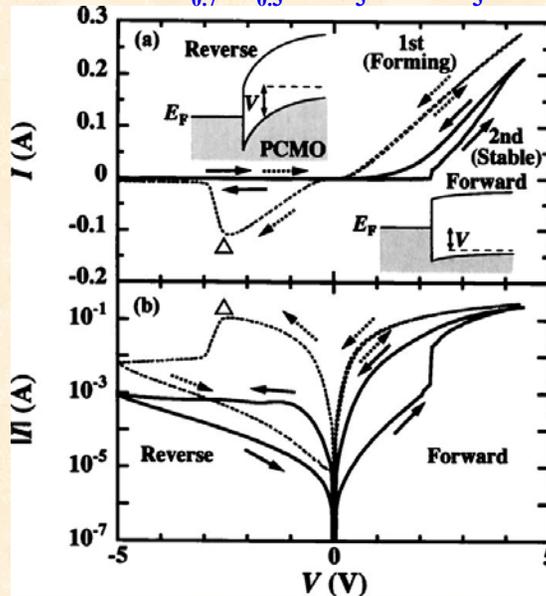
Recent Progress in Resistive Switching Devices

Transitional metal oxide
(NiO, TiO₂, HfO₂, ZrO₂)



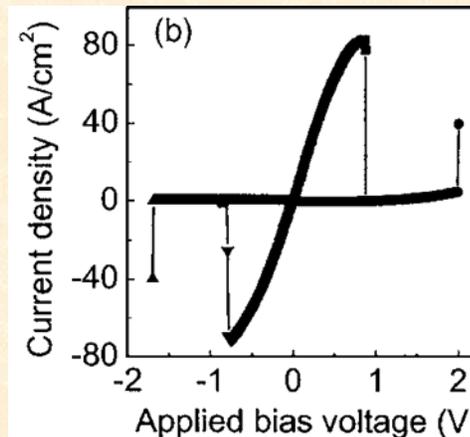
I.G.Baek, et al, IEDM 2004

Ti/Pr_{0.7}Ca_{0.3}MnO₃/SrRuO₃



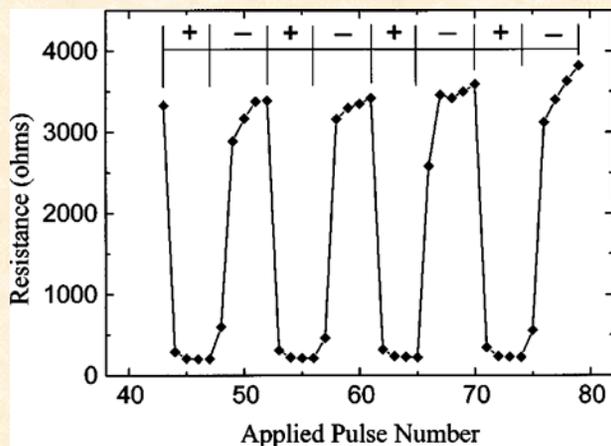
A. Sawa, et al, APL 85, 4073 (2004)

Pt/TiO₂/Ru



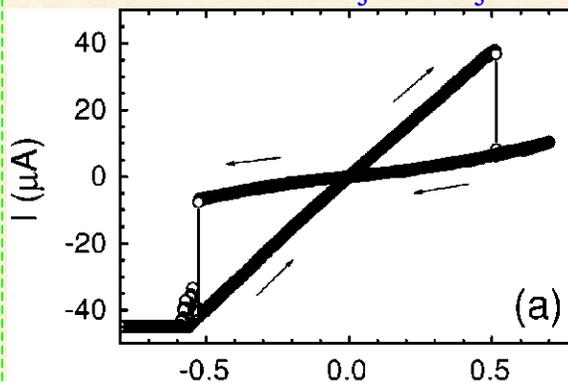
B. J. Choi, et al, JAP 98, 033715 (2005)

Ag/Pr_{0.7}Ca_{0.3}MnO₃/YBa₂Cu₃O_{7-x}



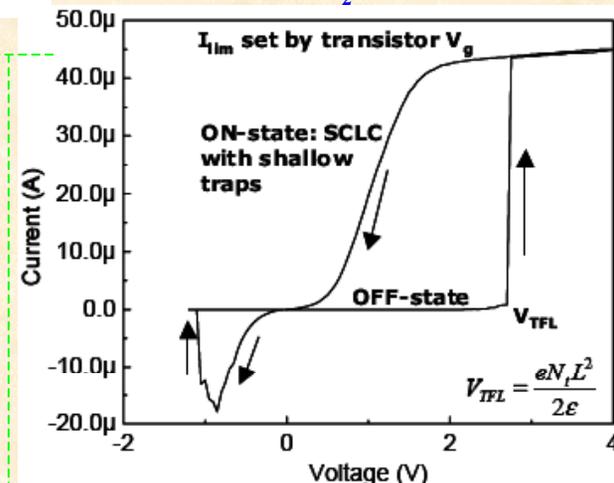
S.Q. Liu, et al, APL 76, 2749 (2000)

Au/SrZrO₃/SrRuO₃



A. Beck, et al, APL 77, 139 (2000)

Ti/Cu₂O/Cu



A. Chen, et al, IEDM 2005

Signatures of Switching Mechanisms

Materials

- Composition/processing effect on switching
- Electrode-dependence

Operation

- Forming process
- Switching polarity-dependence (bipolar vs. unipolar)
- Symmetry in I-V and switching characteristics
- Interface effect (rectifying vs. ohmic I-V)
- Frequency-dependence
- Device size-dependence
- Temperature effect

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Resistive Switching Mechanisms

Resistive Switching mechanisms

Thermal effects

Phase change

Conductive filament induced by partial dielectric breakdown

Electronic effects

Charge trapping

Insulator-metal transition

Modulate bulk electrostatics

Modulate interface barrier

Ionic effects

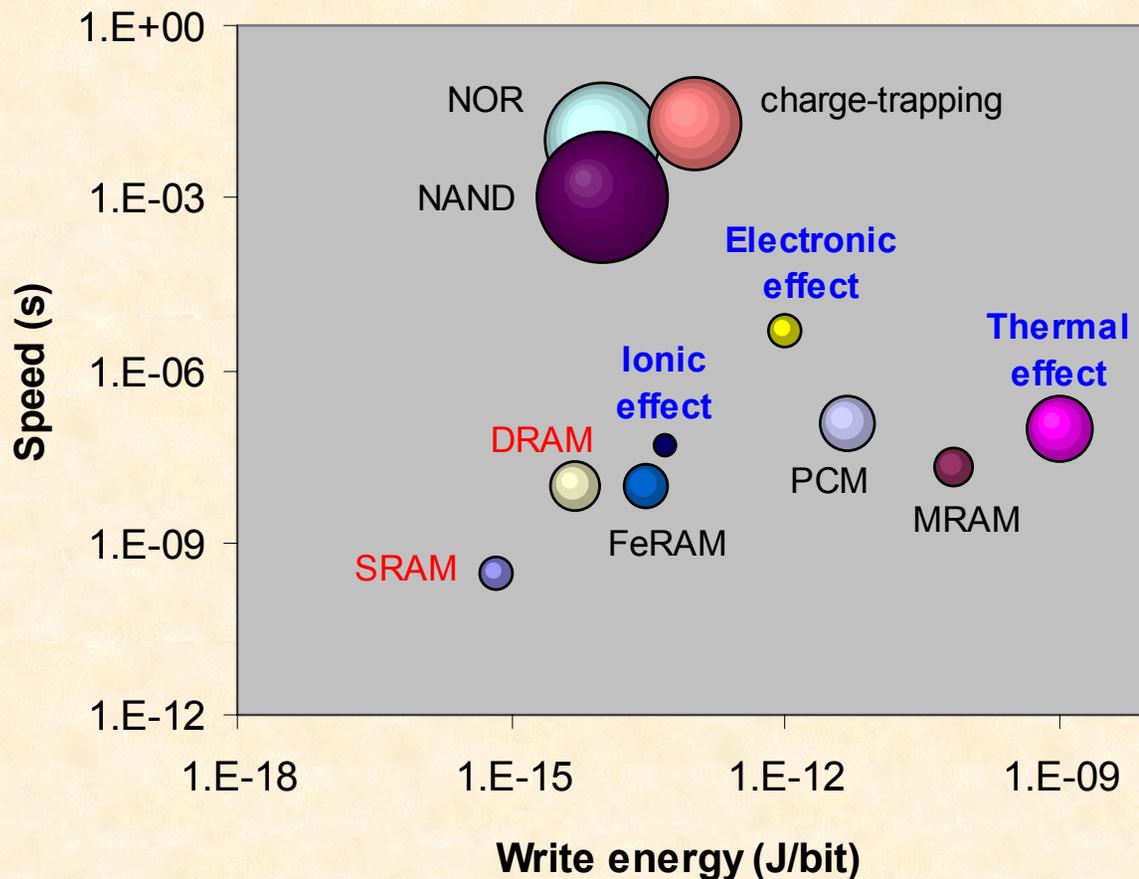
Cation migration

Anion migration

R. Waser, et al, Nat. Mater. 6, 833 (2007)

RRAM Comparison with Other Memories

speed – write energy – operation voltage

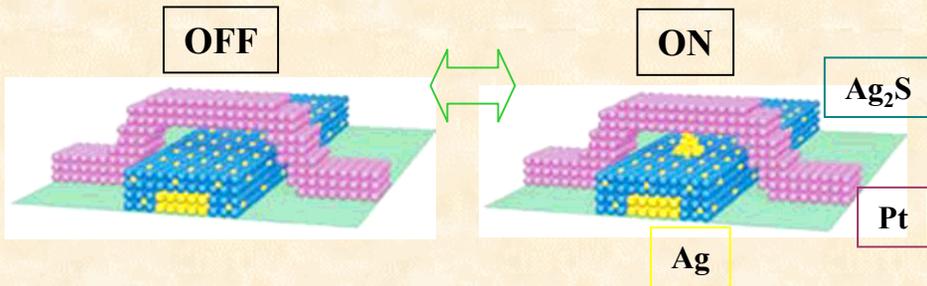


* The symbol size is proportional to the operation voltage of each memory device

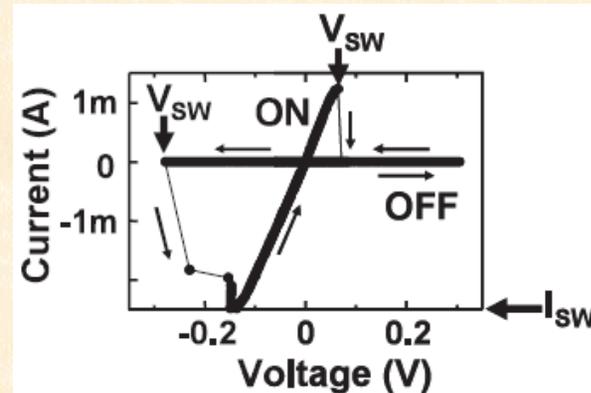
RRAM advantages:

- Non-volatile
- Low voltage
- Low energy
- Fast speed
- Scalable
- Stackable
- CMOS compatible

Resistive Switching in Solid-State Electrolytes

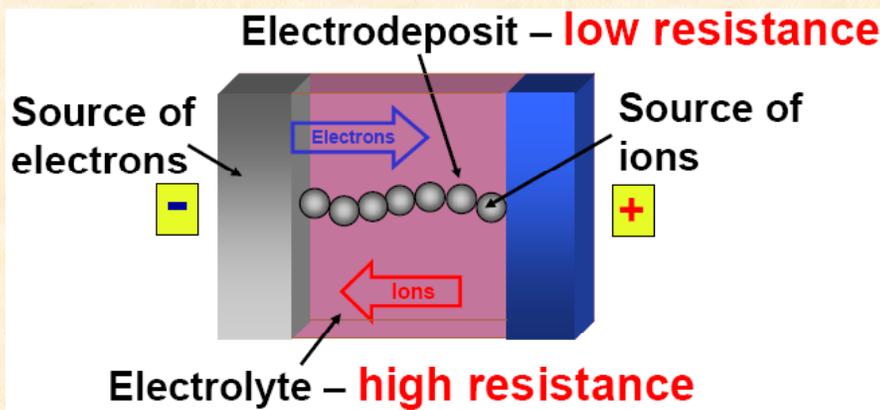


Typical switching I-V



N. Banno, et al,
IEIC Trans.
Electron. **E89**,
1492 (2006)

A quantized conductance switch is formed by electrochemical formation and annihilation of an atomic bridge between an inert electrode and an oxidizable electrode.

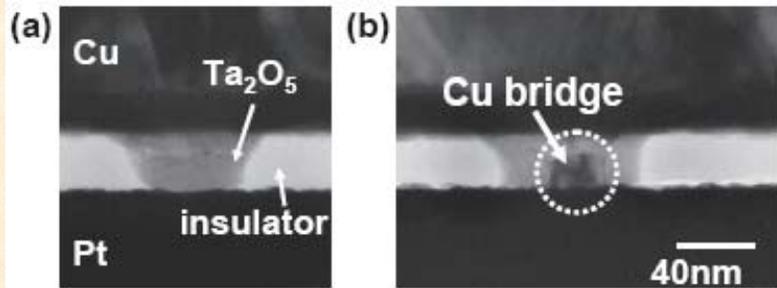


Source: M. Kozicki, ASU

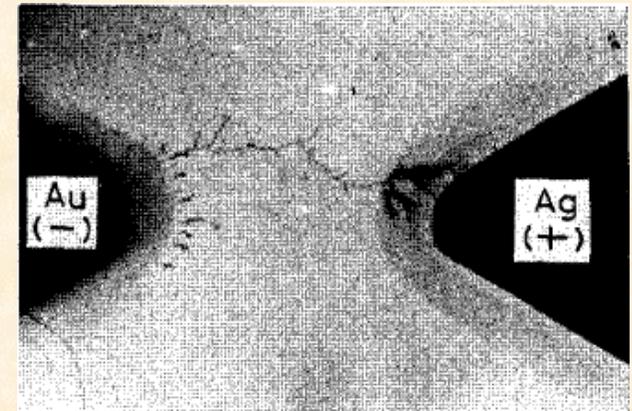
Multiple names for this type of devices

- Atomic switch
- Ionic Memory
- NanoBridge (NEC/JST)
- Solid-State Electrolytic Memory (Sony)
- Programmable Metallization Cell (ASU)
- Conductive Bridging RAM (Qimonda)

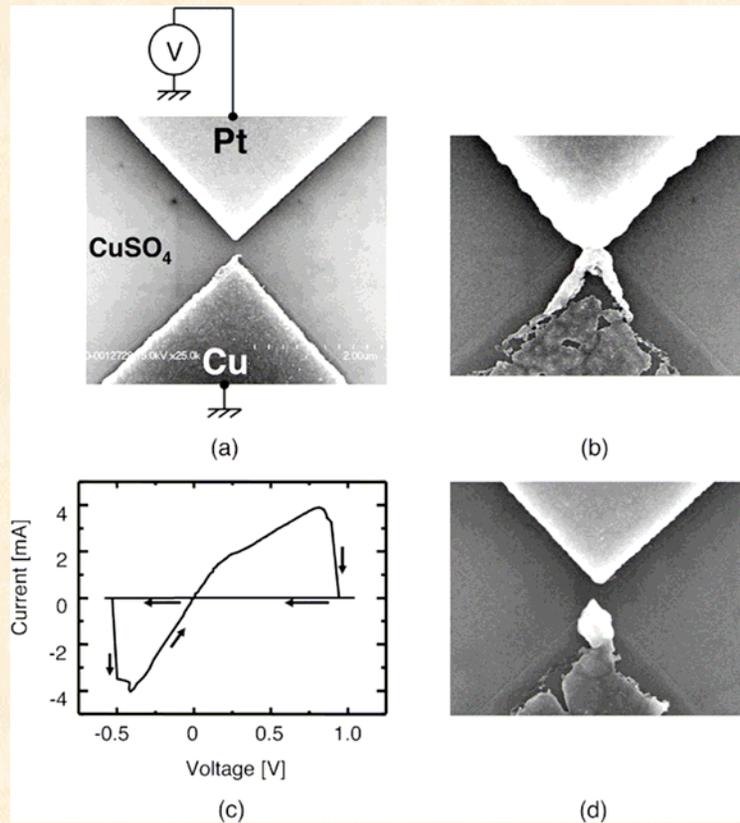
Images of Formation and Annihilation of Conductive Channels



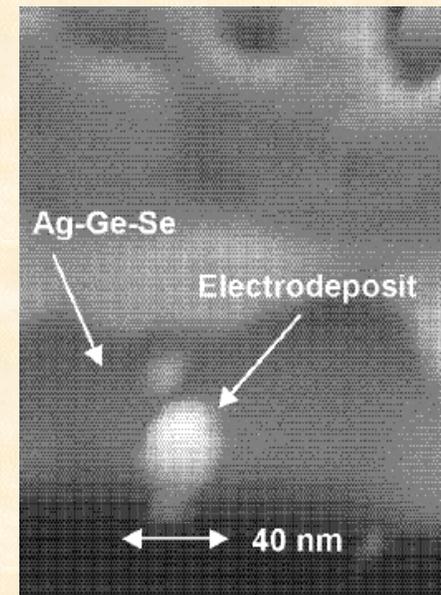
T. Sakamoto, *et al*, Symposium VLSI Tech., pp.38 (2007)



Y. Hirose, *et al*, JAP 47, 2767 (1976)

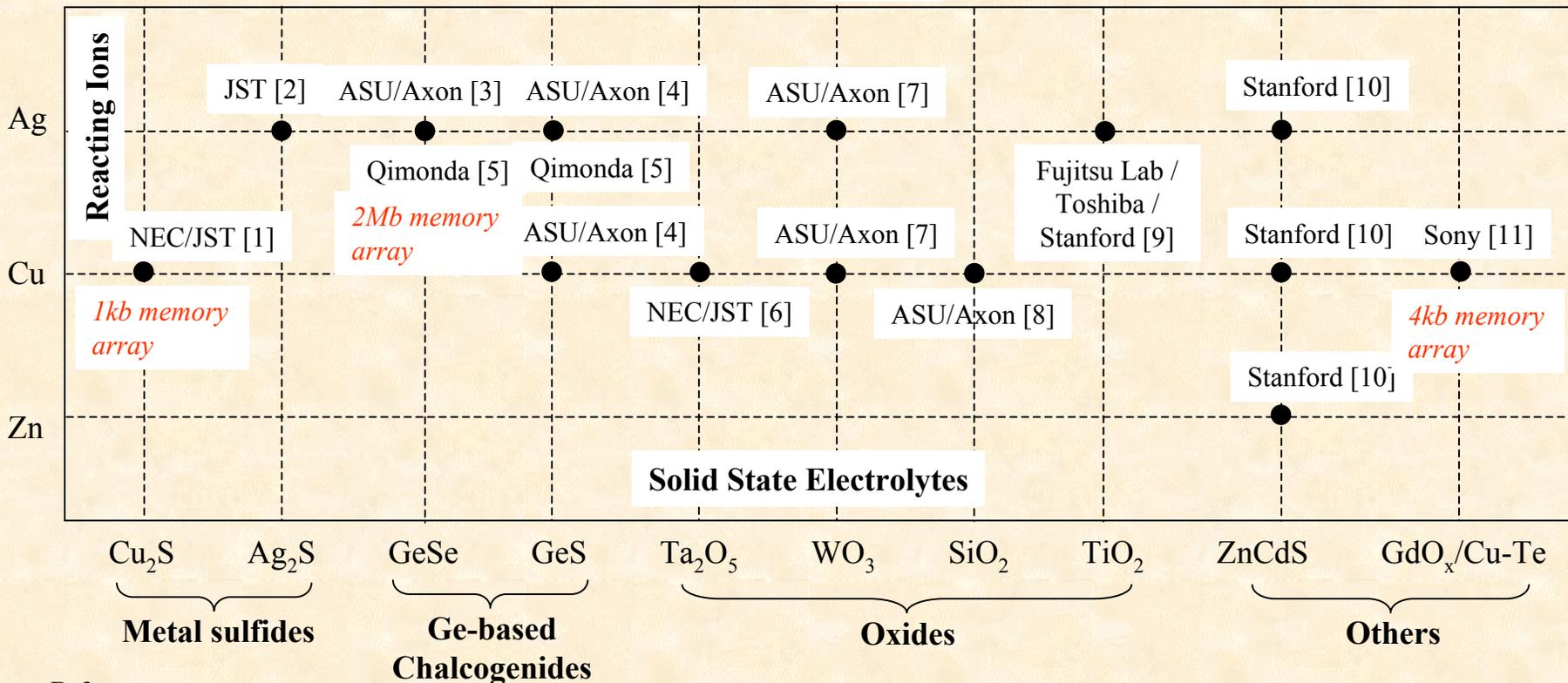


M. Kozicki, *et al*, NVMTS Proceedings, 111 (2006)



S. Kaeriyama, *et al*, IEEE J. Solid-State Circuits **40**, 168 (2005)

Ionic Memory Based on Cation-Migration



References:

1. S. Kaeriyama, *et al*, IEEE J. Solid-State Circuits **40**, 168 (2005);
2. K. Terabe, *et al*, Nature **433**, 47 (2005);
3. M.N. Kozicki, *et al*, IEEE Trans. Nanotech. **4**, 331 (2005);
4. M.N. Kozicki, *et al*, NVMTS proceeding, pp.83 (2005);
5. S. Dietrich, *et al*, IEEE J. Solid-State Circuits **42**, 839 (2007);
6. T. Sakamoto, *et al*, Symposium VLSI Tech., pp.38 (2007);
7. M.N. Kozicki, *et al*, NVMTS, pp.10 (2004);
8. C. Schindler, *et al*, IEEE Trans. Electron Dev. **54**, 2762 (2007);
9. K. Tsunoda, *et al*, Appl. Phys. Lett. **90**, 113501 (2007);
10. Z. Wang, *et al*, IEEE Electron Dev. Lett. **28**, 14 (2007);
11. K. Aratani, *et al*, IEDM Tech. Dig., pp.783 (2007).

Ionic Memory: Device Characteristics

Materials		Sulfides		Chalcogenides			Oxides		
		Ag/Ag ₂ S [1]	Cu/Cu ₂ S [2]	Ag/GeSe [3]	Ag/GeS [4]	Cu/GeS [4]	Cu/Ta ₂ O ₅ [5]	Cu/WO ₃ [6]	Cu/SiO ₂ [7]
Thickness (nm)		-----	~ 40	~ 50	60	60	15	50	12
Device size		150×100nm ²	d = 30nm	d = 75nm	d=240nm	d = 300nm	d=0.2-10μm	d=240nm	d = 1μm
HRS ↑ LRS (DC)	V _{sw} (V)	< 0.4	~ 0.3	~ 0.2	~ 0.45	~ 0.3	~ 2.5	0.4	~ 0.9
	I _{sw} (μA)	-----	2500	10	10	10	100	1	5
LRS ↑ HRS (DC)	V _{sw} (V)	< 0.4	~ 0.1	< 0.5	~ 0.25	< 0.1	~ 1.0	0.2	~ 0.15
	I _{sw} (μA)	-----	1000	< 10	< 10	< 2	~ 1000	< 1	~ 2
Switching time (s)		< 10 ⁻⁶	< 10 ⁻⁴	< 10 ⁻⁷	< 10 ⁻⁷	< 10 ⁻⁷	10 ⁻⁵ -10 ⁻⁴	-----	< 10 ⁻⁶
R_{on} (Ω) / R_{off} (Ω)		10 ³ /10 ⁵	10 ² /10 ⁴	10 ⁴ /10 ⁷	10 ⁴ /10 ¹¹	10 ⁴ /10 ¹⁰	10 ² /10 ⁶	10 ⁵ /10 ⁹	10 ⁴ /10 ⁷
Retention		-----	0.25 yrs	-----	> 10 ⁵ s	-----	10 yrs	>10 ⁴ s	> 10 ⁵ s
Cycle		10 ⁵	> 10 ³	10 ¹¹	-----	-----	10 ⁴	10 ⁵	10 ⁷

* HRS: high resistance state; LRS: low resistance state

References:

1. K. Terabe, *et al*, Nature **433**, 47 (2005);
2. S. Kaeriyama, *et al*, IEEE J. Solid-State Circuits **40**, 168 (2005);
3. M.N. Kozicki, *et al*, IEEE Trans. Nanotech. **4**, 331 (2005);
4. M.N. Kozicki, *et al*, NVMTS proceeding, pp.83 (2005);
5. T. Sakamoto, *et al*, Symposium VLSI Tech., pp.38 (2007);
6. M.N. Kozicki, *et al*, IEEE Trans. Nanotech. **5**, 535 (2006);
7. C. Schindler, *et al*, IEEE Trans. Electron Dev. **54**, 2762 (2007).

Ionic Memory: Array Characteristics

Company		NEC/JSTA ^[1]	Qimonda ^[2]	Sony ^[3]
Tested array size		1 kbit	2 Mbit	4 kbit
Material system		Cu / Cu ₂ S	Ag / GeSe or GeS	Cu-Te / GdO _x
Technology node		250 nm CMOS	90 nm CMOS	180 nm CMOS
Minimum tested cell size		D ~ 30 nm	D = 20 nm	D = 20 nm
Memory structure		1T-1R	1T-1R	1T-1R
Programming (HRS → LRS)	Voltage	1.1 V	≥ 0.6 V	3 V
	Current	-----	10 μA	110 μA
	Pulse width	5 – 32 μs	≤ 50 ns	5 ns
Erasing (LRS → HRS)	Voltage	1.1 V	≤ 0.2 V	1.7 V
	Current	-----	20 μA	125 μA
	Pulse width	5 – 32 μs	≤ 50 ns	1 ns
Retention	Measured	10 ³ s under 35 mV	10 ⁵ s @ 70°C	100 hrs @ 130°C
	Projected	3 months	10 years	10 years
R _{on} / R _{off}		≤ 10 ² Ω / ≥ 10 ³ Ω	10 ⁴ Ω / 10 ¹¹ Ω	10 ⁴ Ω / 10 ⁶ -10 ⁸ Ω
Endurance		10 ³ – 10 ⁴ cycles	10 ⁶ cycles	10 ⁷ cycles
Operating Temperature		-----	≥ 110°C	≥ 130°C

[1] S. Kaeriyama, IEEE JSSC **40**, 168 (2005); [2] S. Dietrich, IEEE JSSC **42**, 839 (2007); [3] K. Aratani, IEDM Tech. Dig., pp.783 (2007)

Compare with Other Resistive Switching Memories

Company		Samsung ^[1]	Spansion ^[2]	Sharp ^[3]	Many others
Tested array size		-----	64 kbit	64 bit	Many binary and complex metal oxides have been tested on resistive switching properties, e.g., TiO _x , ZrO, Nb ₂ O ₅ , V ₂ O ₅ , SrTiO ₃ , SrZrO ₃ , LaMnO ₃ , <i>etc.</i> The switching mechanisms are controversial.
Material system		TMO (e.g., NiO)	TMO (e.g., Cu ₂ O)	Pr _{0.7} Ca _{0.3} MnO	
Technology node		180 nm CMOS	180 nm CMOS	0.5 μm CMOS	
Minimum tested cell size		D ~ 70 nm	D ~ 180 nm	D = 0.8 μm	
Memory structure		1T-1R	1T-1R	1T-1R	
Programming (HRS → LRS)	Voltage	< 3 V	~ 3 V	~ 5 V	
	Current	< 1 mA	< 100 μA	< 200 μA	
	Pulse width	< 10 ns	< 50 ns	~ 20 ns	
Erasing (LRS → HRS)	Voltage	< 1 V	< 1.5 V	~ 5 V	
	Current	< 2 mA	< 100 μA	< 200 μA	
	Pulse width	< 5 μs	< 50 ns	~ 10 ns	
Retention	Measured	8 months	10 ⁵ s @ 90°C	-----	
	Projected	10 years	10 years	-----	
R _{on} / R _{off}		~500 Ω / ~50 kΩ	< 50 kΩ / > 1 MΩ	< 100 kΩ / > 1M Ω	
Endurance		10 ⁶ cycles	> 10 ³ cycles	10 ⁵ cycles (?)	
Operating Temperature		300°C	> 90°C	> 200°C	

[1] I.G. Baek, IEDM Tech. Dig., pp.587 (2004); [2] A. Chen, IEDM Tech. Dig., pp.765 (2005); [3] W.W. Zhuang, IEDM Tech. Dig., pp.193 (2002)

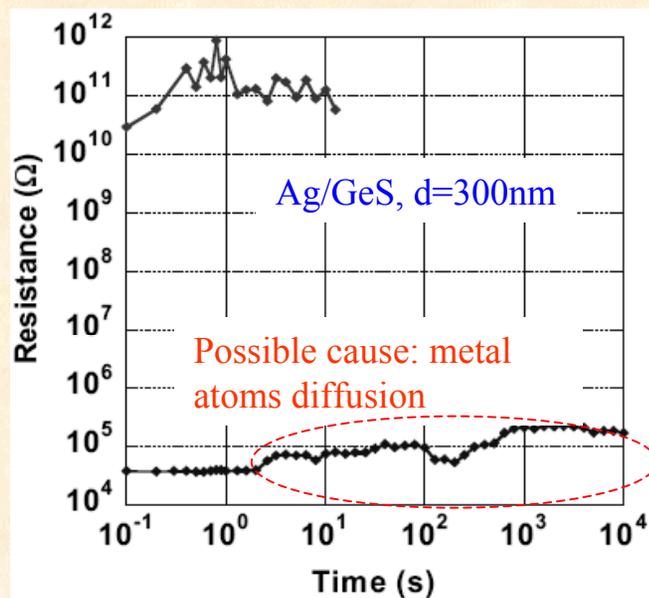
Ionic Memory: Advantages vs. Challenges

Advantages	Challenges
<ul style="list-style-type: none">• Scalable• Compatible with CMOS• Low switching voltage/current• Nonvolatile switching states• Stackable for 3D IC• (Relatively) well-understood mechanism	<ul style="list-style-type: none">• Reliability / endurance• Switching speed• Operating temperature• Defect/fault tolerance• Mixed mechanisms

Other features
<ul style="list-style-type: none">• Low processing temperature• Potential for novel architectures

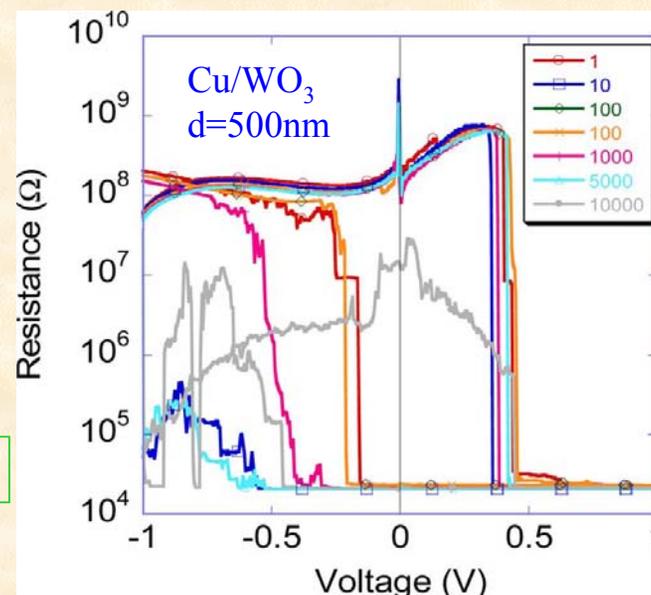
Ionic Memory: Reliability Issues

Reliability concerns	Possible effects
<ul style="list-style-type: none"> Over-programming or over-erasing 	<ul style="list-style-type: none"> R_{on}/R_{off} variation; cycling failure
<ul style="list-style-type: none"> Random diffusion of migrating ions 	<ul style="list-style-type: none"> Variation in switching parameters
<ul style="list-style-type: none"> Diffusion of metal atoms 	<ul style="list-style-type: none"> R_{on} variation; retention failure
<ul style="list-style-type: none"> Temperature sensitivity 	<ul style="list-style-type: none"> Material degradation; switching failure
<ul style="list-style-type: none"> Inherent impurities 	<ul style="list-style-type: none"> Poor uniformity; instability



Retention

Endurance

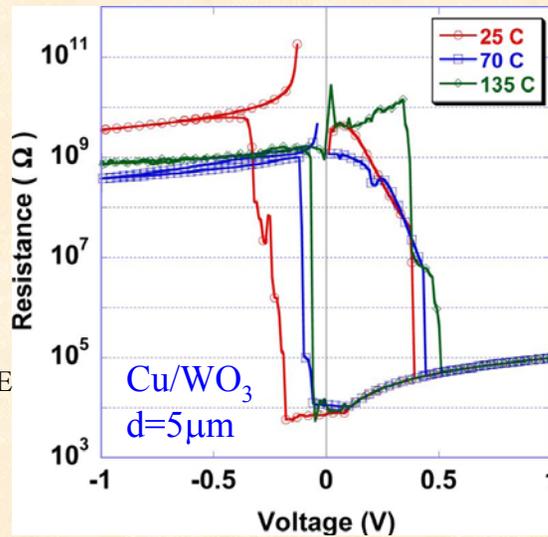


M.N. Kozicki, et al, NVMTS proceeding, pp.83 (2005)

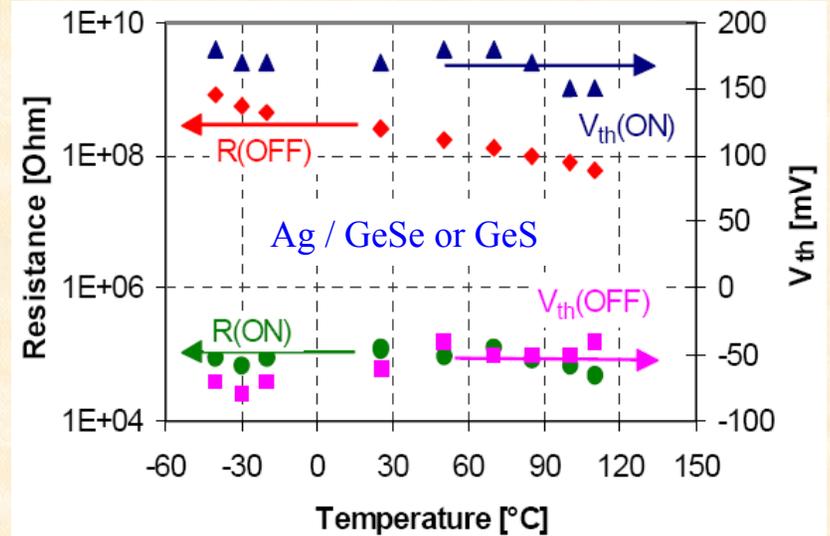
M.N. Kozicki, et al, IEEE Trans. Nanotech. 5, 535 (2006)

Ionic Memory: Reliability Issues

Temperature effect

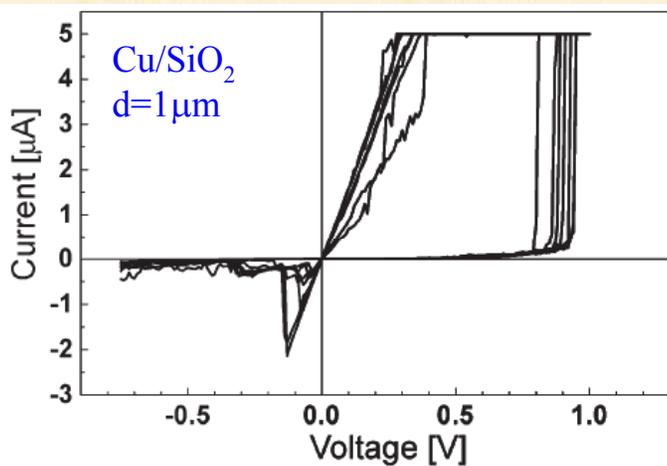


M.N. Kozicki, et al, IEEE Trans. Nanotech. 5, 535 (2006)

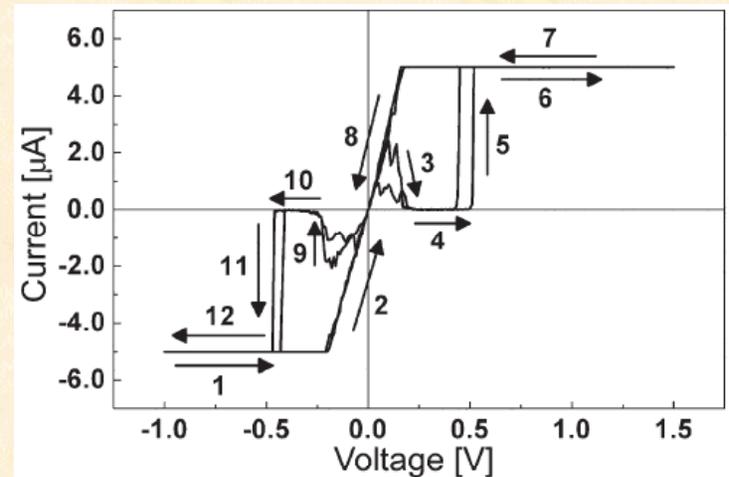
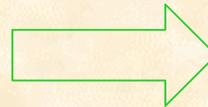


S. Dietrich, et al, IEEE JSSC 42, 839 (2007)

Mixed switching types



Bipolar to unipolar

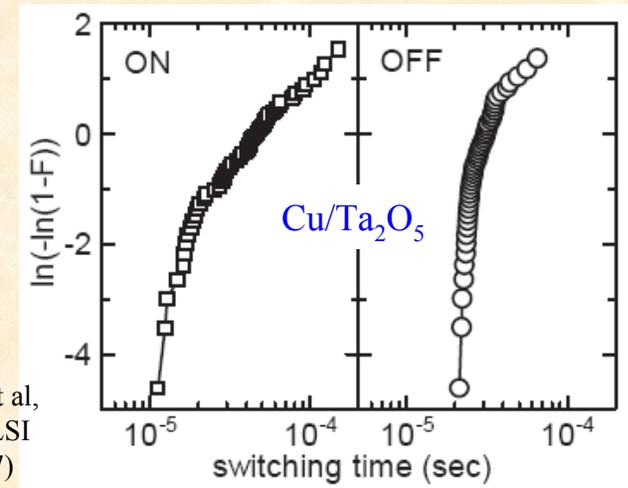


C. Schindler, et al, IEEE Trans. Electron Dev. 54, 2762 (2007)

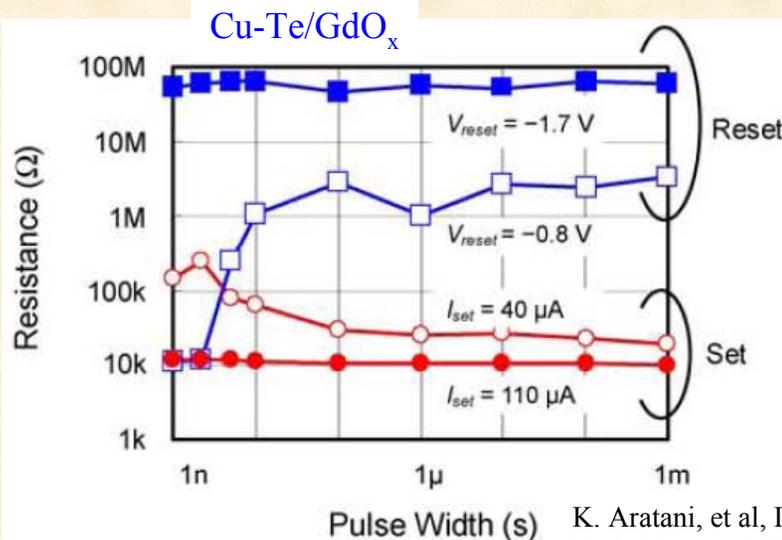
Ionic Memory: Switching Speed

Switching = Ion migration in solid electrolyte + Electrochemical reaction at cathode

- Switching speed is determined by the speed of ion migration and electrochemical reaction
- Large variation on switching speed across different material systems (maybe due to parasitic RC delay)
- Switching speed on the order of ns has been demonstrated in chip-level measurement

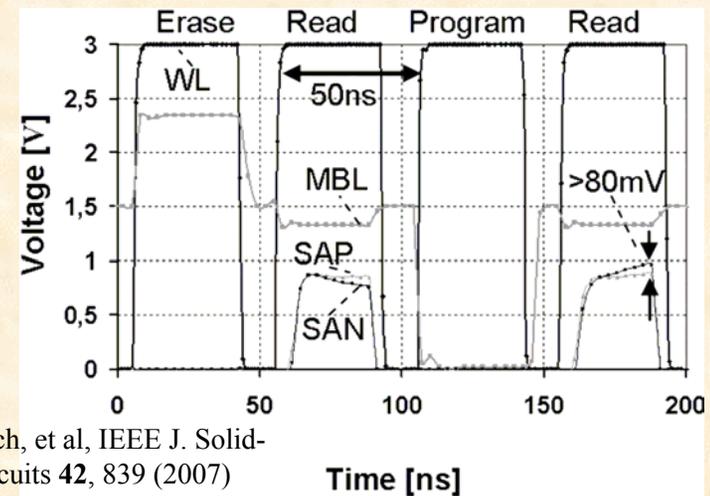


T. Sakamoto, et al, Symposium VLSI Tech., 38 (2007)



K. Aratani, et al, IEDM Tech. Dig., pp.783 (2007)

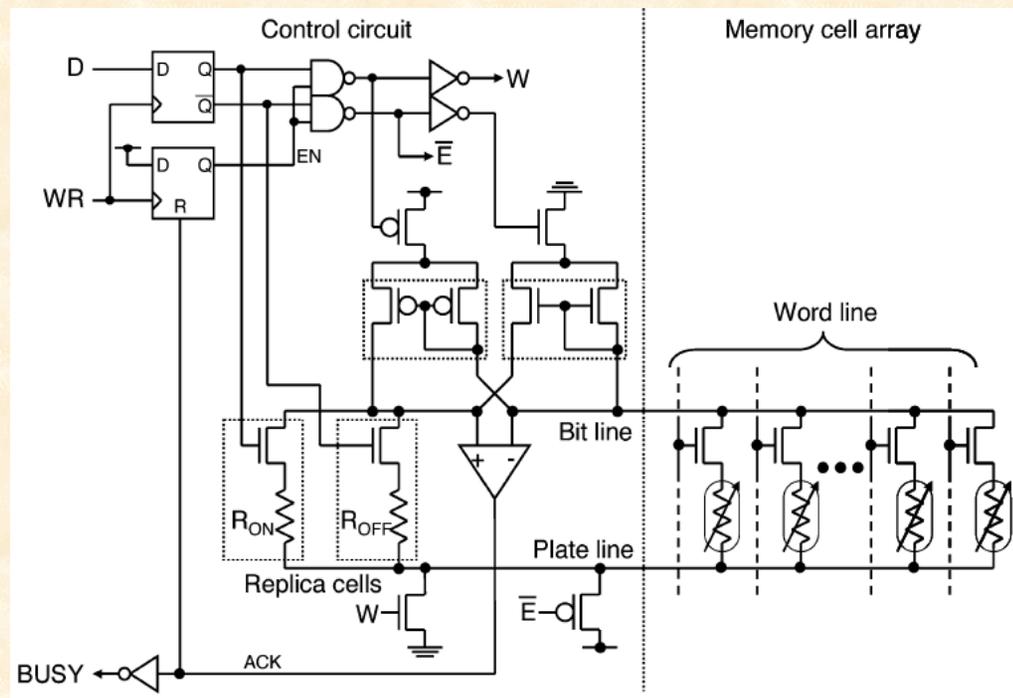
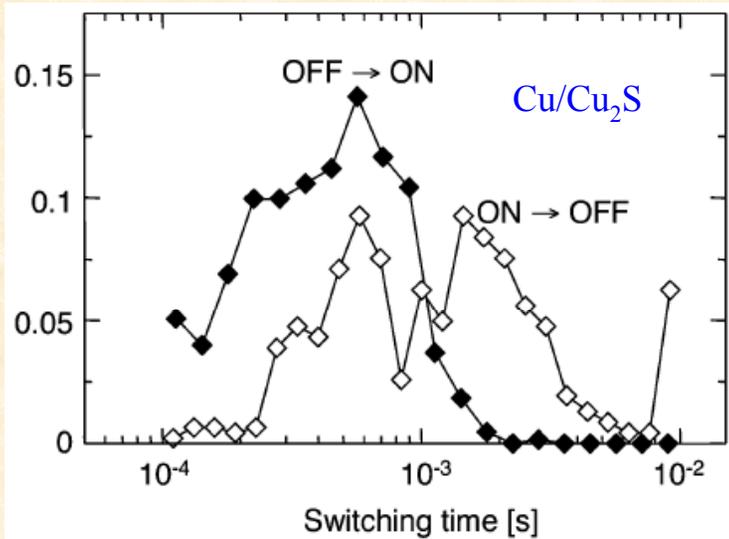
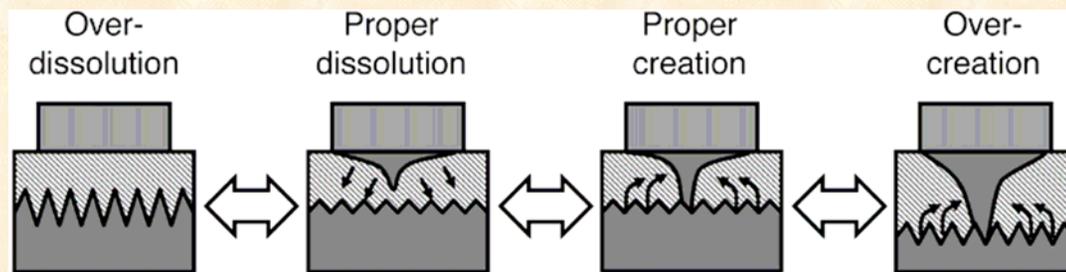
Ag / GeSe or GeS



S. Dietrich, et al, IEEE J. Solid-State Circuits 42, 839 (2007)

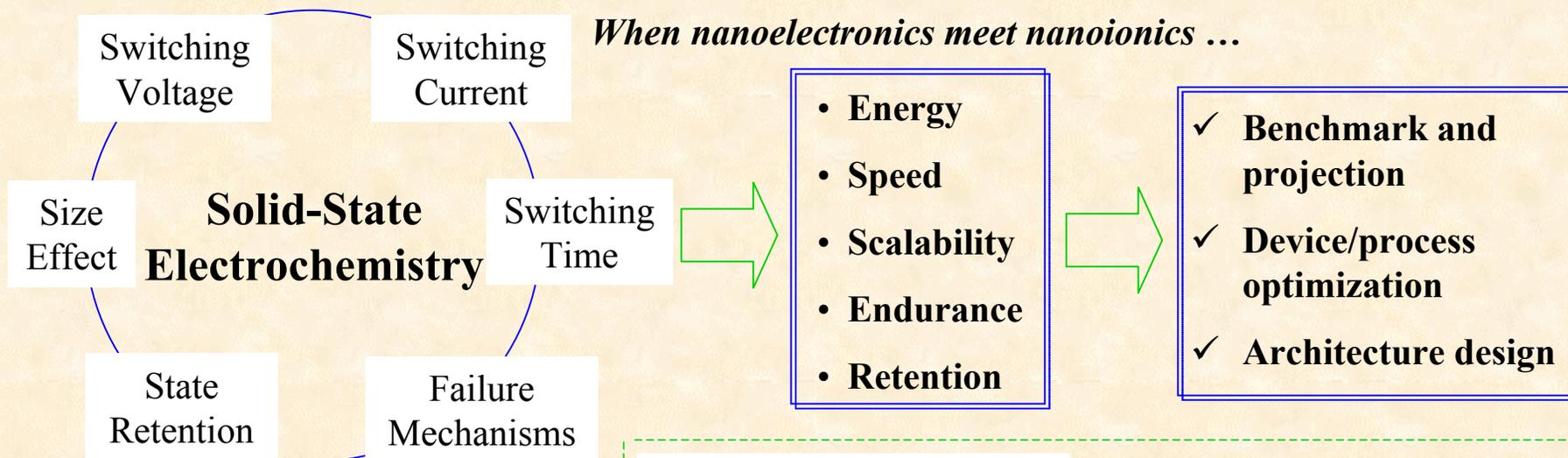
Ionic Memory: Over-Programming, Over-Erasing

Over-programming and over-erasing lead to long switching time, large variation on switching parameters, and short endurance. Sensing/control circuits are needed to alleviate this problem.



S. Kaeriyama, et al, IEEE J. Solid-State Circuits **40**, 168 (2005)

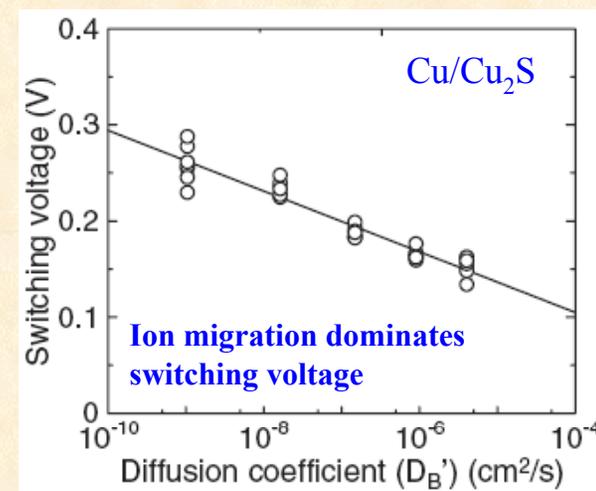
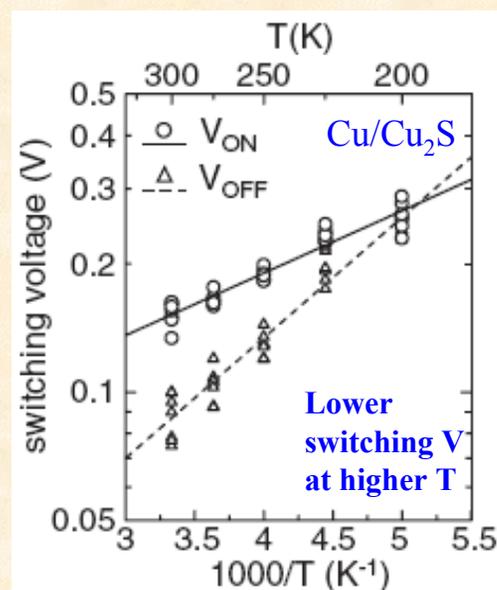
Quantitative Modeling of Ionic Memory



Many questions to be addressed:

- Microscopic nature of the cation conduction paths?
- Details of electrode reactions?
- Impact of thermal effects?
- Fundamental speed limits?
- Fundamental scaling limits?
- Temperature effects?
- Failure mechanisms?

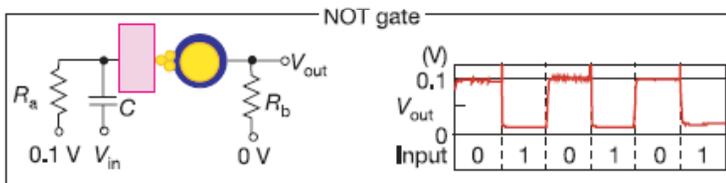
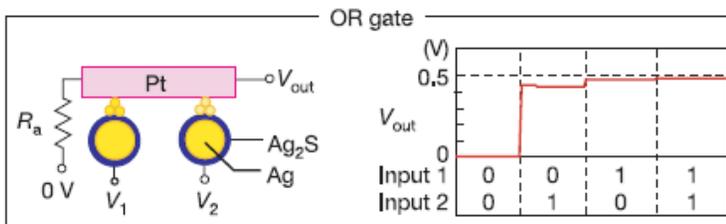
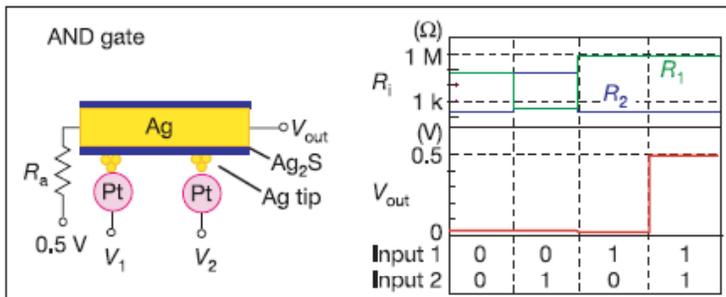
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N. Banno, et al, Jpn J. Appl. Phys.
45, 3666 (2006)

Novel Logic Gates Based on Hysteretic Resistors

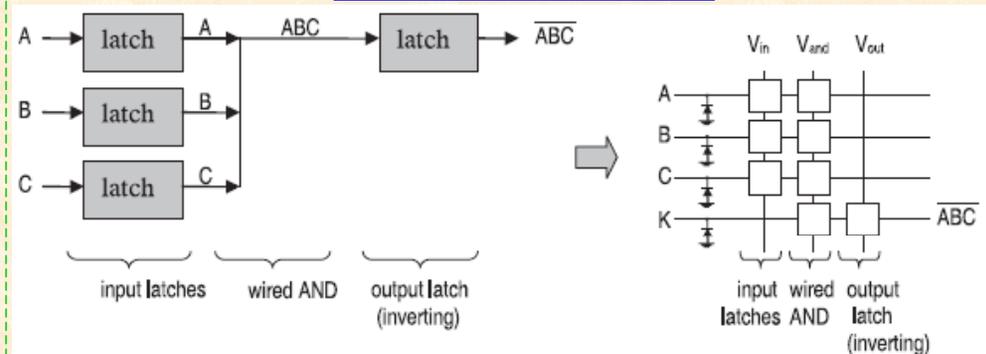
Logic gates based on atomic switch



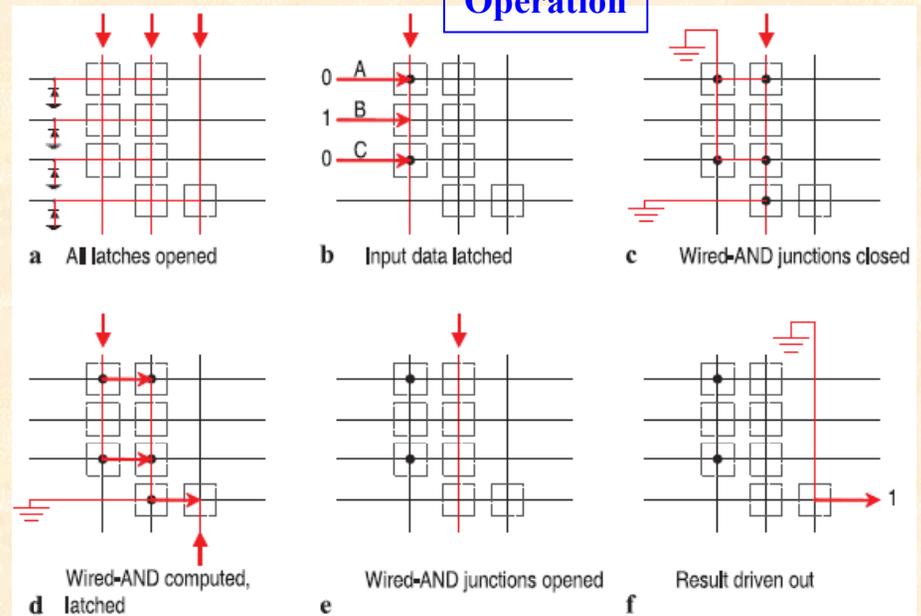
Logic gates configured with QCASs. **a**, Schematic diagram of an AND gate using QCASs (left) and its operating result (right). **b**, Schematic diagram of the OR gate (left) and its operating result (right). **c**, Schematic diagram of the NOT gate (left) and its operating result (right). Resistors R_a (10 k Ω) and R_b (1 k Ω), and a capacitor C (100 pF), are used. V_1 and V_2 are applied as input bias voltages. Input level 1 is 0.5 V for the AND and OR gates, and 1.5 V for the NOT gate. Input level 0 is 0 V for all gates. Input levels were changed every second.

K. Terabe, et al, Nature **433**, 47 (2005)

Crossbar NAND gate

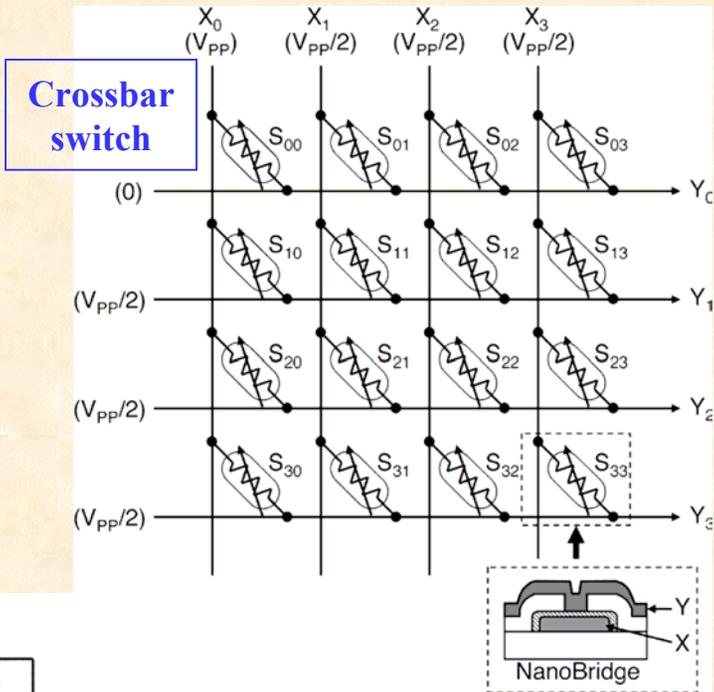
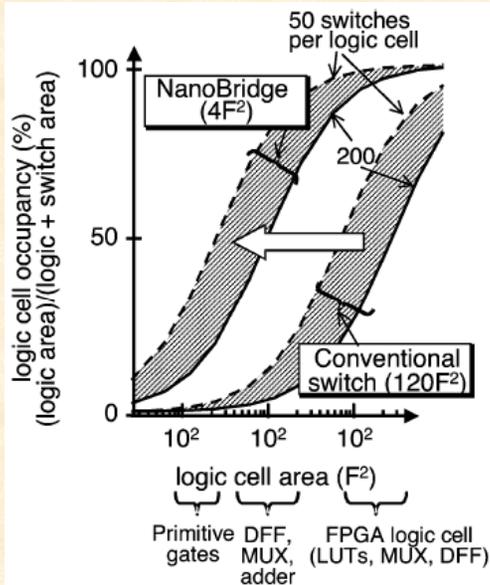


Operation

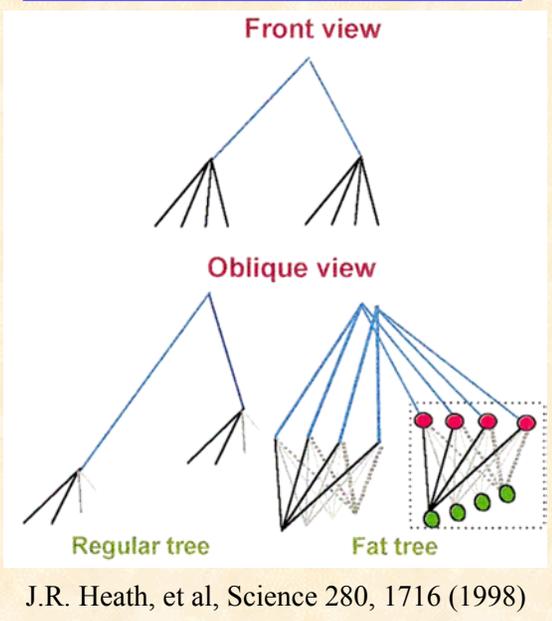


G. Snider, Appl.Phys. A **80**,1165 (2005)

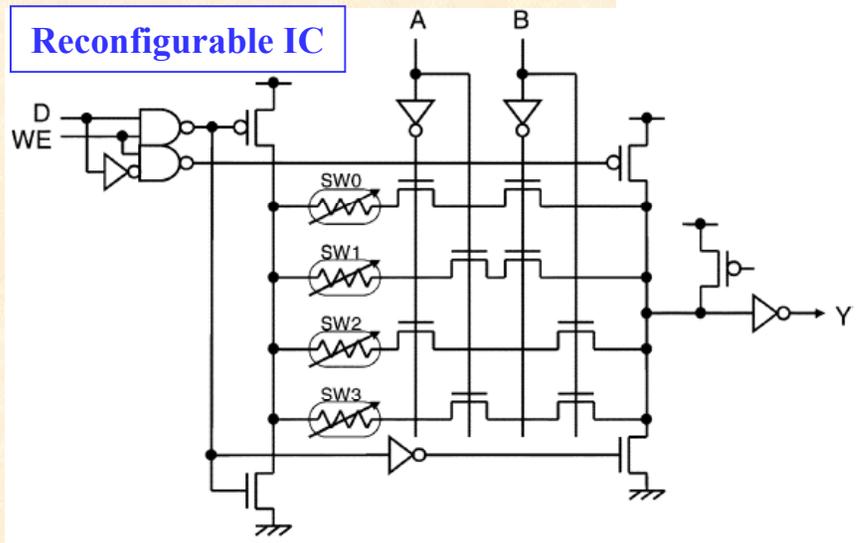
Novel Architectures



Defect-tolerant architectures



Reconfigurable IC



Inputs				Output		
WE	A	B	D	Y	Operation	
1	0	0	0	-	Turns SW0 off	Programming operations
1	0	1	1	-	Turns SW1 on	
1	1	0	1	-	Turns SW2 on	
1	1	1	0	-	Turns SW3 off	Logic operations
0	0	0	-	0	Evaluates SW0 state	
0	0	1	-	1	Evaluates SW1 state	
0	1	0	-	1	Evaluates SW2 state	
0	1	1	-	0	Evaluates SW3 state	

- : don't care or unstable

S. Kaeriyama, et al, IEEE J. Solid-State Circuits 40, 168 (2005);

Summary

- Resistive switching memories involves multiple switching mechanisms.
- Ionic memory devices have the advantages in scalability, energy efficiency, and compatibility with CMOS.
- The major challenges of ionic memory are reliability and speed.
- Novel logic gates and architectures may be possible for resistive switching devices, e.g., reconfigurable IC, stackable memory, defect-tolerant architecture, *etc* .